Docket No.

206342US2

IN RE APPLICATION OF: Toshifumi NAGAIWA, et al.

FILED:

SERIAL NO: 09/840,178

FOR:

April 24, 2001

WORKTABLE DEVICE AND PLASMA PROCESSING APPARATUS FOR SEMICONDUCTOR PROCESS

"RESPONSE UNDER 37 CFR 1.116-1

GROUP 1963

EXPEDITED PROCEDURE EXAMINING

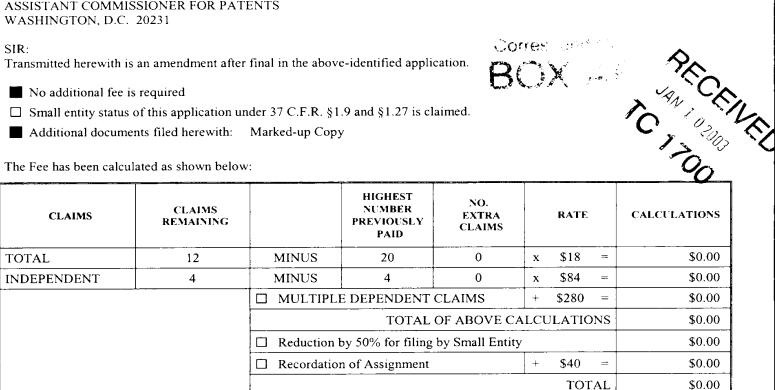
ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment after final in the above-identified application.

- No additional fee is required
- ☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- Additional documents filed herewith: Marked-up Copy

The Fee has been calculated as shown below:



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- Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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